

## LPM2001 Schedule At-A-Glance

Wednesday, May 16		Thursday, May 17		Friday, May 18		
Conference Hall (7 <sup>th</sup> Floor)	Training Room (6 <sup>th</sup> Floor)	Conference Hall (7 <sup>th</sup> Floor)	Training Room (6 <sup>th</sup> Floor)	Conference Hall (7 <sup>th</sup> Floor)	Training Room (6 <sup>th</sup> Floor)	
9:00am-10:00am Registration		9:00am-10:30am Session4A: Optics Fabrication <i>Chair: Gillner A.</i>	9:00am-10:30am Session4B: Fundamental Aspects (1) <i>Chair: Liu D.M.</i>	9:00am-10:30am Session7A: Microsystems and Microelements <i>Chair: Konov V.V.</i>	9:00am-10:30am Session7B: Laser Cleaning Workshop <i>Chair: Fotakis C.</i>	
10:00am-10:10am Opening Remarks <i>Miyamoto I.</i>						
10:10am-12:10pm Session 1: Overview <i>Chair: Sugioka K.</i>	10:30am-10:50am Coffee Break			10:30am-10:50am Coffee Break	10:30am-10:40am Coffee Break	
	10:50am-12.20pm Session5A: Microfabrication and Microstructuring <i>Chair: Helvajian H.</i>		10:50am-12:30pm Session5B: Fundamental Aspects (2) <i>Chair: Veiko V.P.</i>	10:50am-12.20pm Session8A: Industrial Applications (1) <i>Chair: Sepold G.</i>	10:40am-12:40pm Session 8B: Laser Cleaning Workshop <i>Chair:Takai M.</i>	
Lunch 12:10pm-1:40pm		Lunch 12:20pm-1:30pm		Lunch 12:20pm-1:20pm	Lunch 12:40pm-1:20pm	
		Poster Presentation 1:30pm-2:30pm		Poster Presentation 1:20pm-2:20pm		
1:40pm-3:10pm Session2A: Ultrafast Laser (1) <i>Chair: Mazur E.</i>	1:40pm-3:10pm Session2B: System and Optics (1) <i>Chair: Gower M.C.</i>	2:30pm-4:40pm Session6A: Advanced Microfabrication Technology <i>Chair: Holmes A.</i>	2:30pm-4:40pm Session6B: Pulsed Laser Deposition <i>Chair: Okada T.</i>	2:20pm-4:00pm Session9A: Industrial Applications (2) <i>Chair: Washio K.</i>	2:20pm-3:20pm Session9B: Laser Cleaning Workshop <i>Chair: Arnold N.</i>	
					3:20pm-4:20pm Session10B: Laser Cleaning Workshop <i>Chair: Grigoropoulos C.P</i>	
3:10pm-3:30pm Coffee Break		4:40pm-5:00pm Transport to Cruise		4:00pm-4:20pm Coffee Break	4:20pm-4:30pm Coffee Break	
3:30pm-5:00pm Session3A: Ultrafast Laser(2) <i>Chair: Masuhara H.</i>	3:30pm-4:50pm Session3B: System and Optics (2) <i>Chair:Jitsuno T.</i>			4:20pm-6:00pm Session10A: Industrial Applications (3) <i>Chair: Dausinger F.</i>	4:30pm-5:50pm Session11B: Modification <i>Chair: Hong M.H.</i>	
		5:00pm-5:20pm Coffee Break			4:50pm-5:20pm Coffee Break	5:00pm-8:00pm Cruise Excursion
5:20pm-7:20pm Rump Session <i>Chairs: Dunsky C., Hoving W.</i>						